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PATENT

Attorney Docket No. 211843-00032

IN THE U.S. PATENT AND TRADEMARK OFFICE

Application No.: 10/519,699
I.A. Filing Date: June 26, 2003
Inventor(s): Horsky, et al.
Title: Ion Implantation Device and a Method of Semiconductor Manufacturing
by the Implantation of Boron Hydride Cluster Ions
Group Art Unit No.: 2881
Confirmation No.: 6928

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to examining the instant application on the merits, please enter the following preliminary amendment.

Amendment to the Specification is reflected on page 2.

Remarks begin on page 3 of this paper.